

# NASA SBIR Success Story:- Active Edge-Control in Polishing of Mirror Segments and Other Applications

David D. Walker

Research Director, Zeeko Ltd

Professor of Optics, Glyndŵr University, N. Wales

Professorial Research Associate, University College London

OptIC

glyndŵr  
PRIFYSGOL GLYNDŴR WRECSAM  
GLYNDŴR UNIVERSITY WREXHAM

 UCL

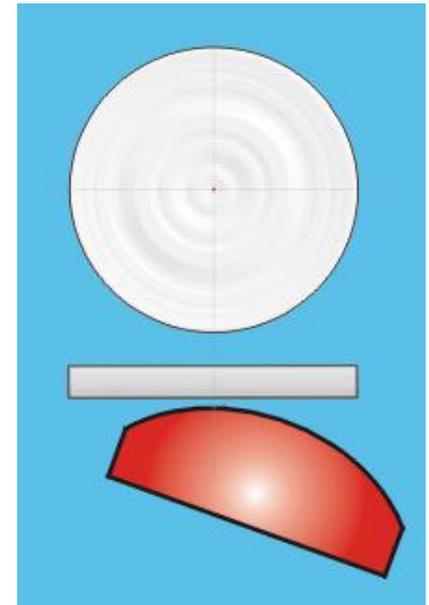
 ZEEKO<sup>Ltd</sup>

# This talk

- Starting-point – NASA SBIR grant
- E-ELT and prototype segments
- Another application of edge-control
- Acknowledgements

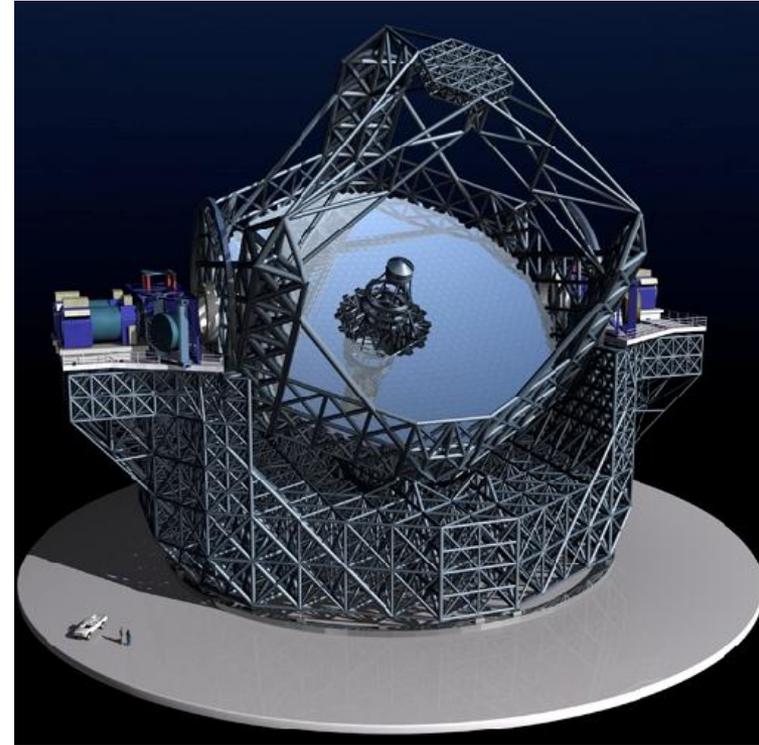
# NASA SBIR grant

- “Edge Control in Large Segmented Optics Using Zeeko Polishing Technology”, Proposal S4.04-9574
- Demonstrated the basic method
  - Compressible spherical bonnet
  - Rotated and axis precessed
  - Tool compressed against the part
  - Delivers variable spot-size



# The 39.3m aperture European Extremely Large Telescope

- Segmented primary mirror
  - 798 hexagonal segments +133 spares
  - Each 1.4m a/corners
  - Irregular hexagons
  - 50mm thick
  - ~ 200 microns max asphericity



Prototype segments near edge of primary. Reflect the earlier 42m telescope design with 84m ROC segments.

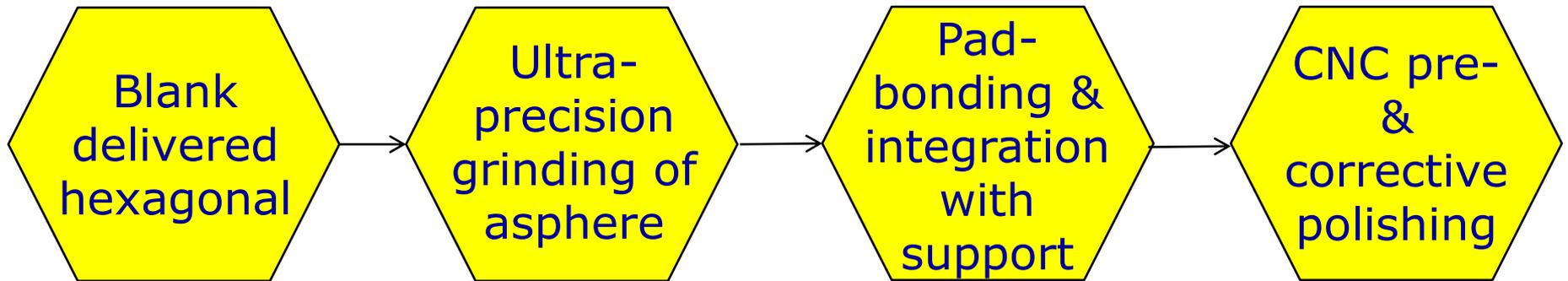
# Segment production-rate & quality

- Construction schedule:- 2-3 segments per week
- Segment warping harness in the telescope will remove most of the low-order aberrations

| ESO specification (abridged!)                     | Average      | Maximum      |
|---------------------------------------------------|--------------|--------------|
| RMS surface form (excluding 10mm edge-zone)       | <b>25nm</b>  | <b>50nm</b>  |
| RMS surface form (ESO Zernike allowances removed) | <b>7.5nm</b> | <b>15nm</b>  |
| PVq (95%) edge mis-figure (surface) in edge-zone  | <b>100nm</b> | <b>200nm</b> |

- RMS surface form *includes* errors in *matching* segment base-radii and conic-constants

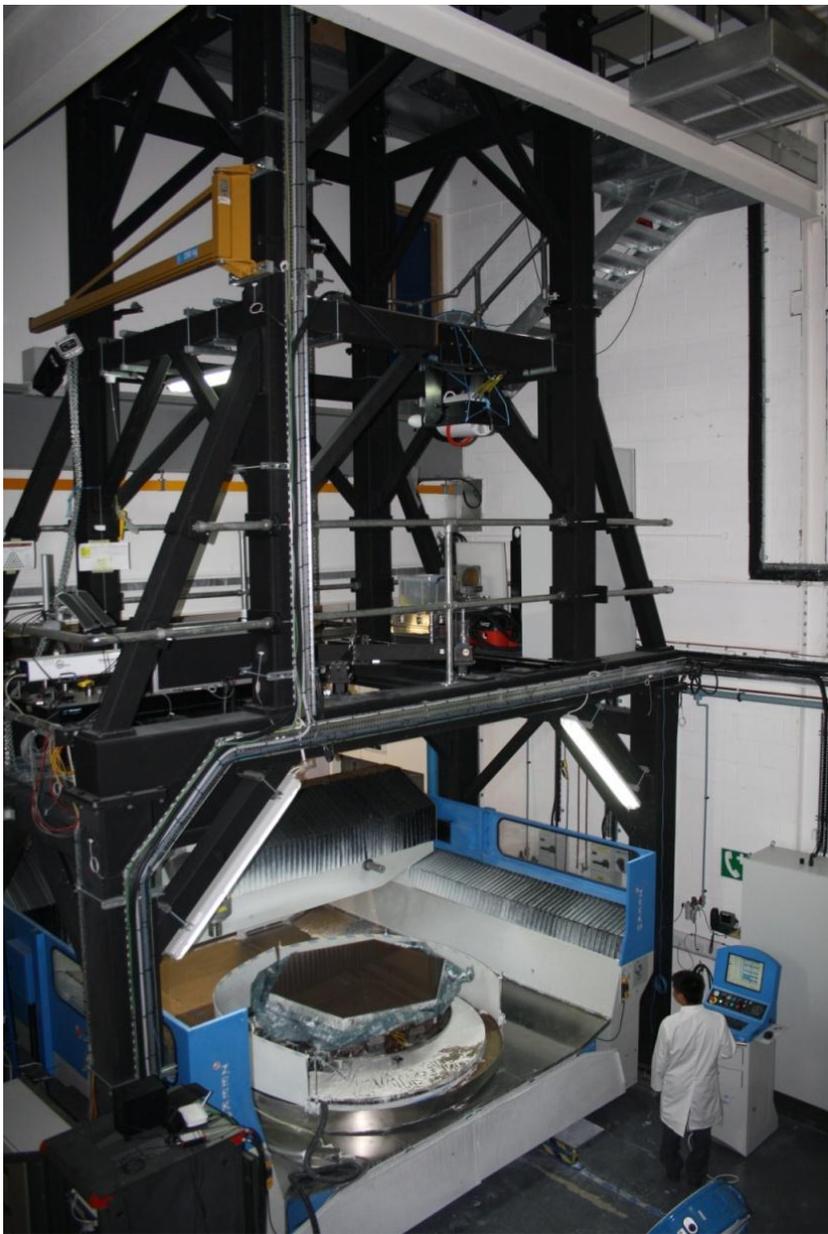
# Process-chain and metrology



In-situ metrology

# National Facility for Ultra Precision Surfaces

Hosted by OpTIC in North Wales  
Operated by Glyndŵr University



Zeeko IRP1600  
under test-tower  
On-axis optical test

On-machine  
deployment of  
pentaprism  
profilometer

OpTIC

glyndŵr  
PRIFYSGOL GLYNDŴR WRECSAM  
GLYNDŴR UNIVERSITY WREXHAM

 UCL

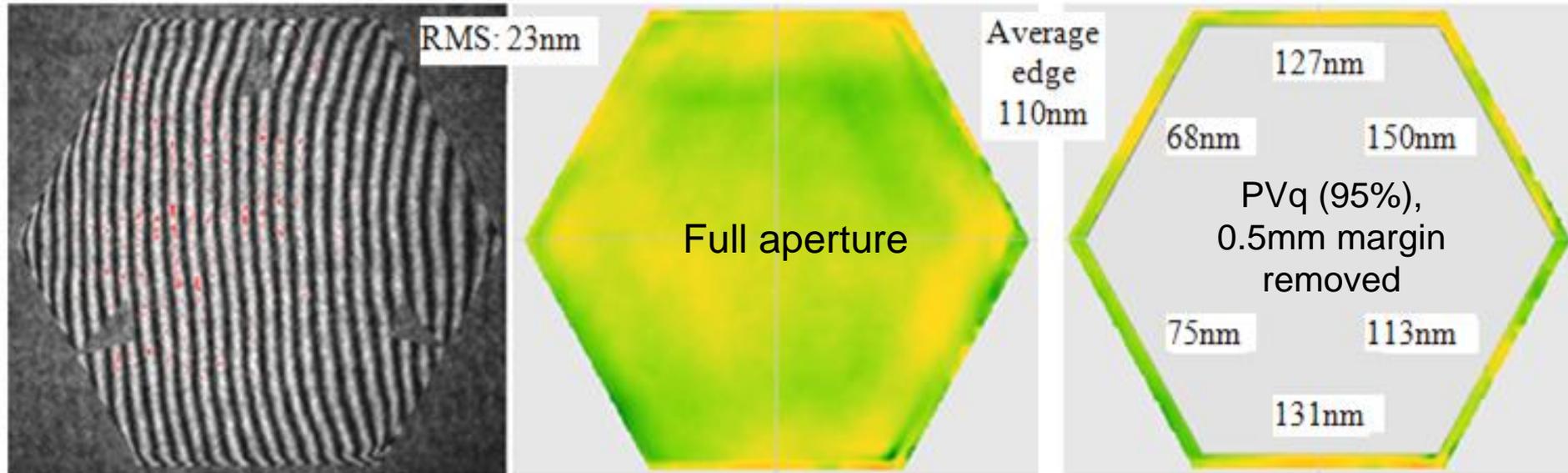


ZEEKO<sup>7</sup> Ltd

# Edge-polishing strategy

1. CNC-grind the off-axis asphere
2. Apply 0.5mm of the final 1mm bevel
3. Bonnet polishing programmed to leave turned-up edge at every stage
4. Up-turn progressively narrowed and lowered
5. Hard pitch tool to remove residual up-stand
6. Final 0.5mm bevel applied at end

# Repeated edge-trials on 400mm borosilicate spherical parts



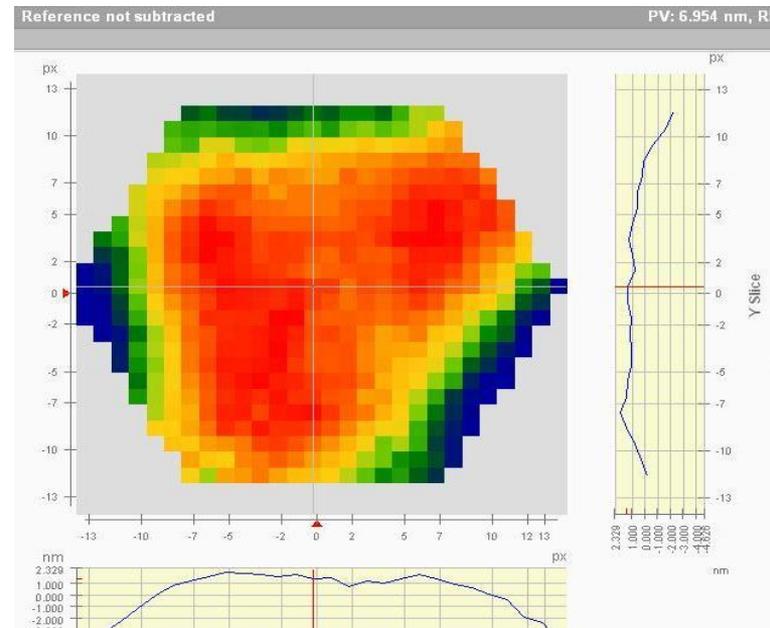
In 10mm wide edge zone (to start of bevel):-

**110nm PVq surface** edge-misfigure (average over 6 edges)

# Grinding 1<sup>st</sup> aspheric segment SPN01 (Zerodur)



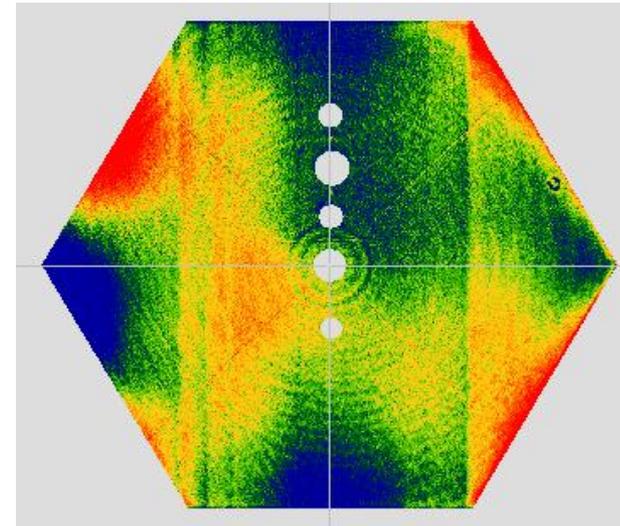
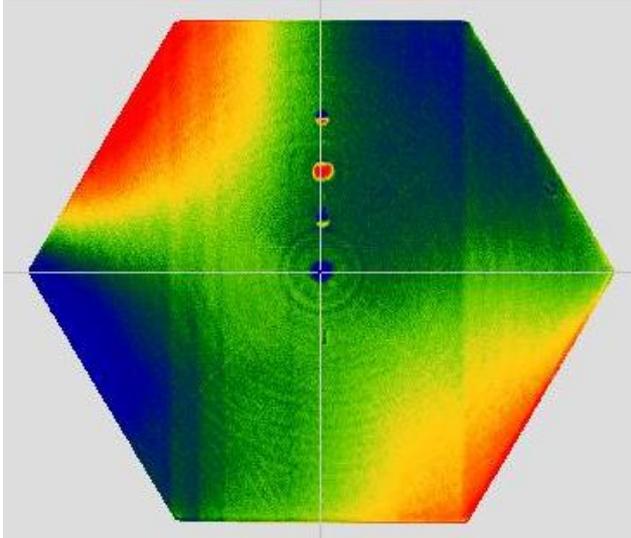
- Cranfield University BoX™ m/c
- Built by Cranfield Precision Ltd
  - **6.5μm PV** measured on grinding platen (Cranfield Univ. CMM)
  - **~ 150nm** mid-spatials



CMM data on 50mm grid, by courtesy Cranfield University

# Zeeko polishing SPN01

- Used extensively for equipment / process / metrology / software de-bugging and qualification

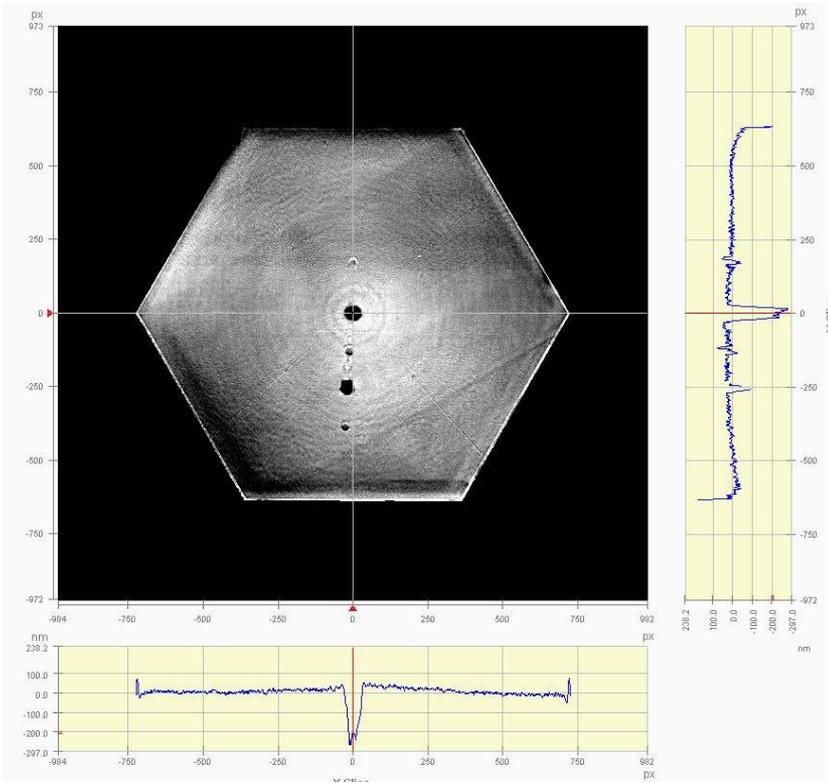


- SPN01 then held, due to Test Tower thermal issues
- Now rectified:- stable to  $\sim \pm 0.25$  degs C

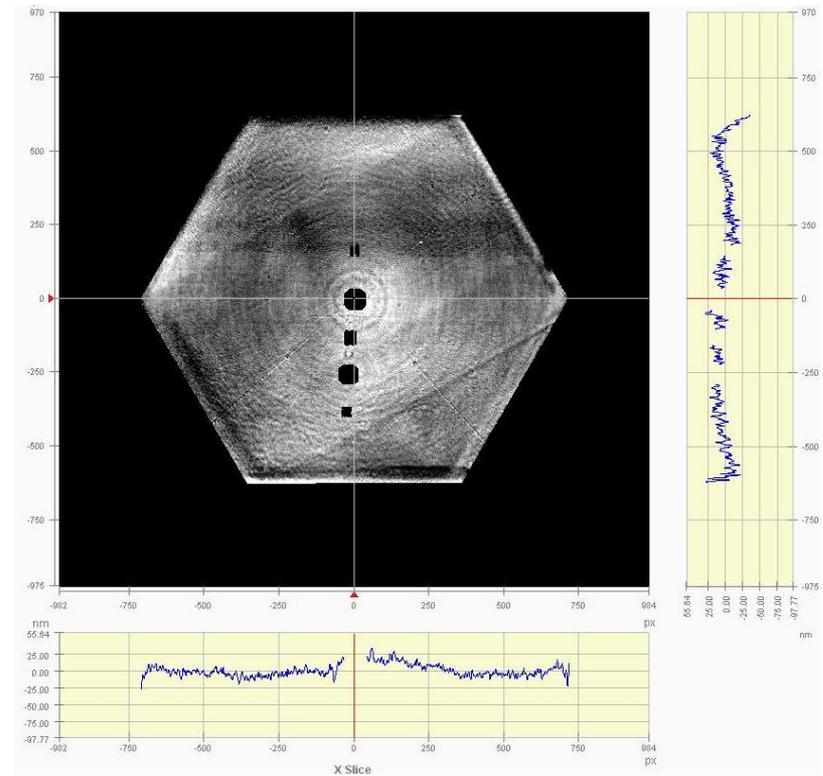
# BoX grinding SPN04      Corning ULE

- Again, mounted on diamond-turned platen
- After grinding,  $\sim 2\mu\text{m}$  “flash pre-polish”
  - Measured on **27 point hydrostatic** support
  - Grinding form-error **> 40  $\mu\text{m}$  PV** (4X expected)
    - grinding support ?
    - springing due to “Twyman effect” ?
- Needed to remove  $> 60\mu\text{m}$  DC material in polishing and retain quality of edges.

# SPN04 under acceptance ... this week!

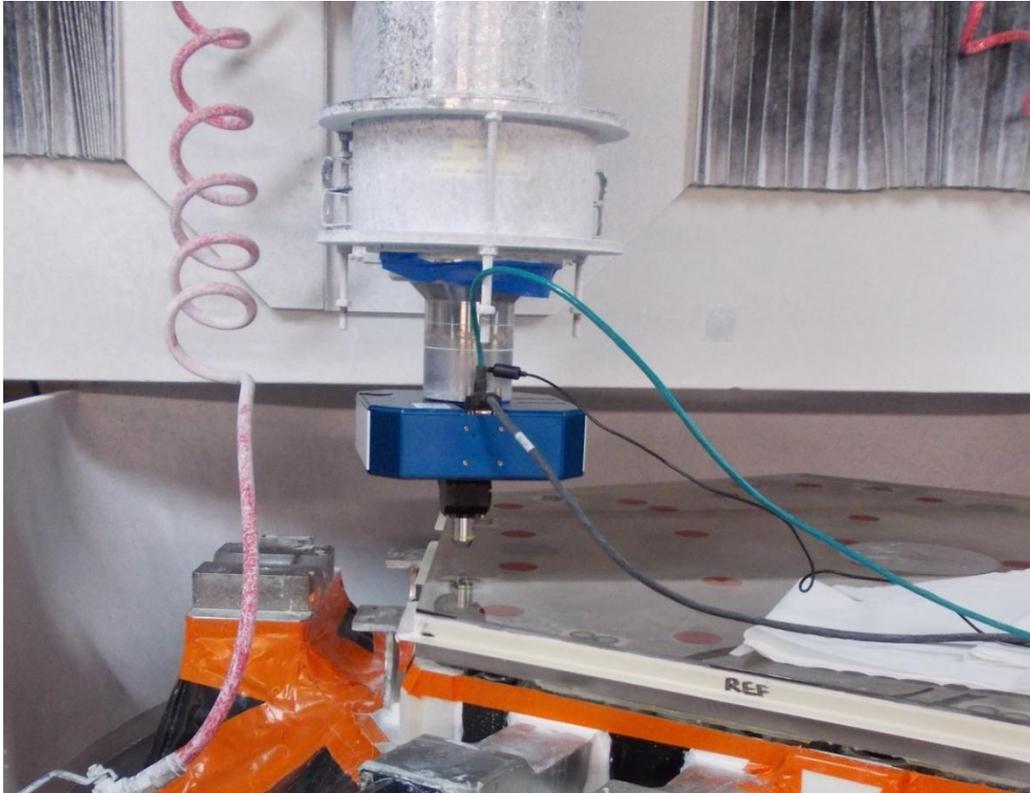


Full Aperture to edge  
Only tip/tilt removed  
**22.9nm RMS Surface**



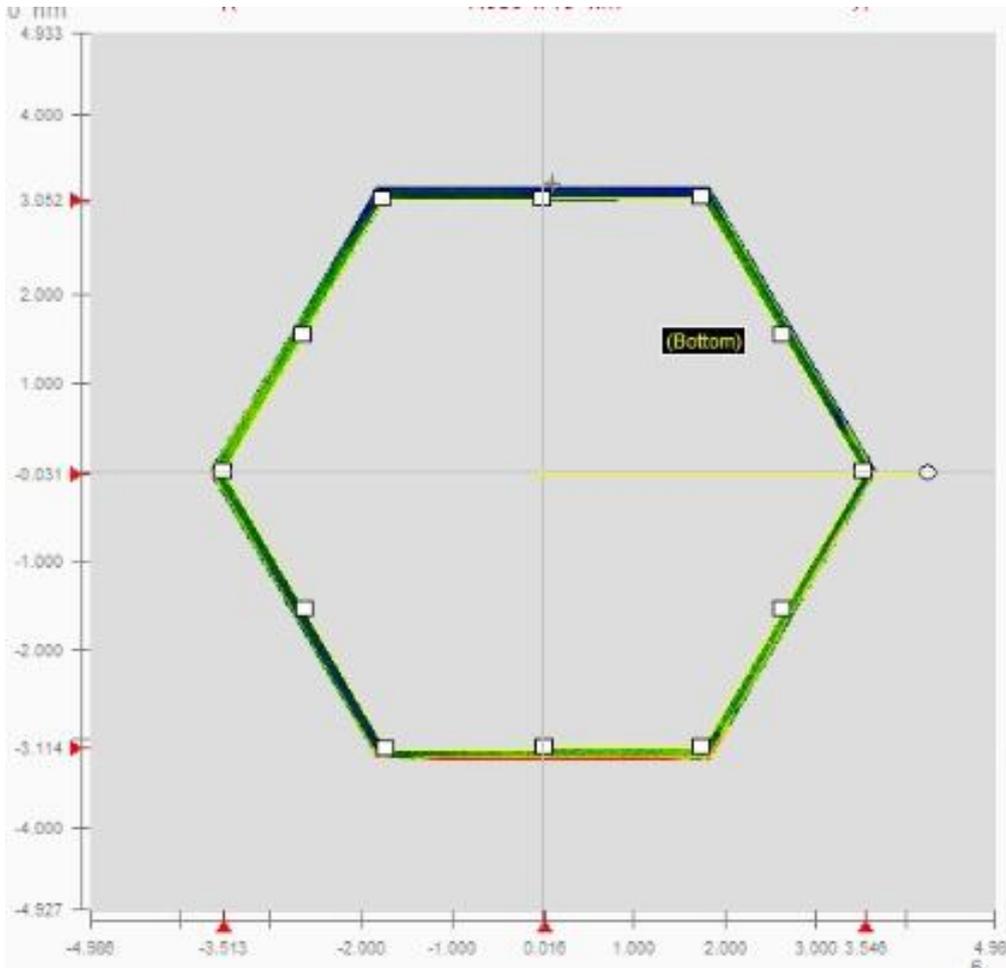
10mm edge zone cropped  
ESO low-order allowances removed  
CGH artifacts masked  
**10.3nm RMS Surface**

# 3D Surface-texture measurement



- 4D Technologies STA1 white-light interferometer
- Mounted in Zeeko machine tool-holder
- Automated for multiple sample-areas
- SPN04 – uniform texture  
**~1nm Sq**

# Edge result on SPN04



- Final 0.5mm of bevel still to be applied
- Phase-map cropped
  - Leaving 10mm wide edge-zone
  - Edges turned up
  - Average mis-figure over six edges is:-

**172nm PVq (95%) surface**

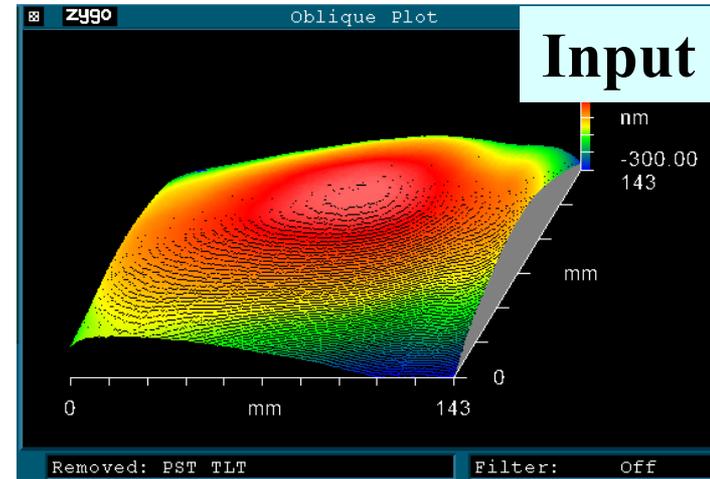
# EUV photolithography photomasks

- Photomasks
  - Fused silica window + chrome pattern
  - One photomask needed for each layer in a wafer
- Next-generation EUV photomasks:-
  - 30-100nm PV form error
  - Edge dead-zone < 5mm wide
- With standard CMP on square blanks – tough!

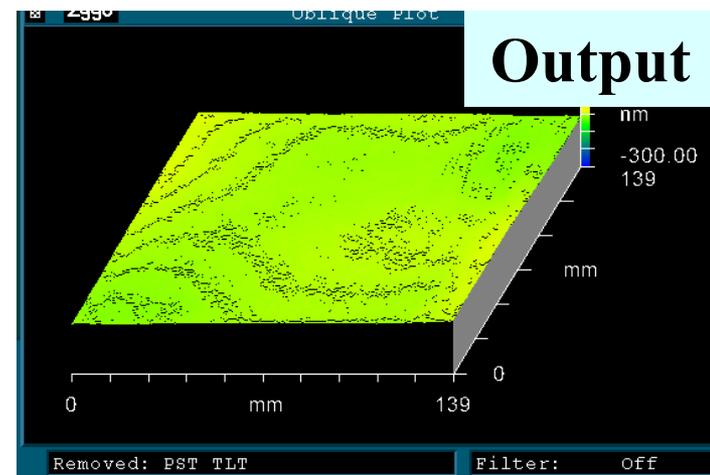
# Photomasks



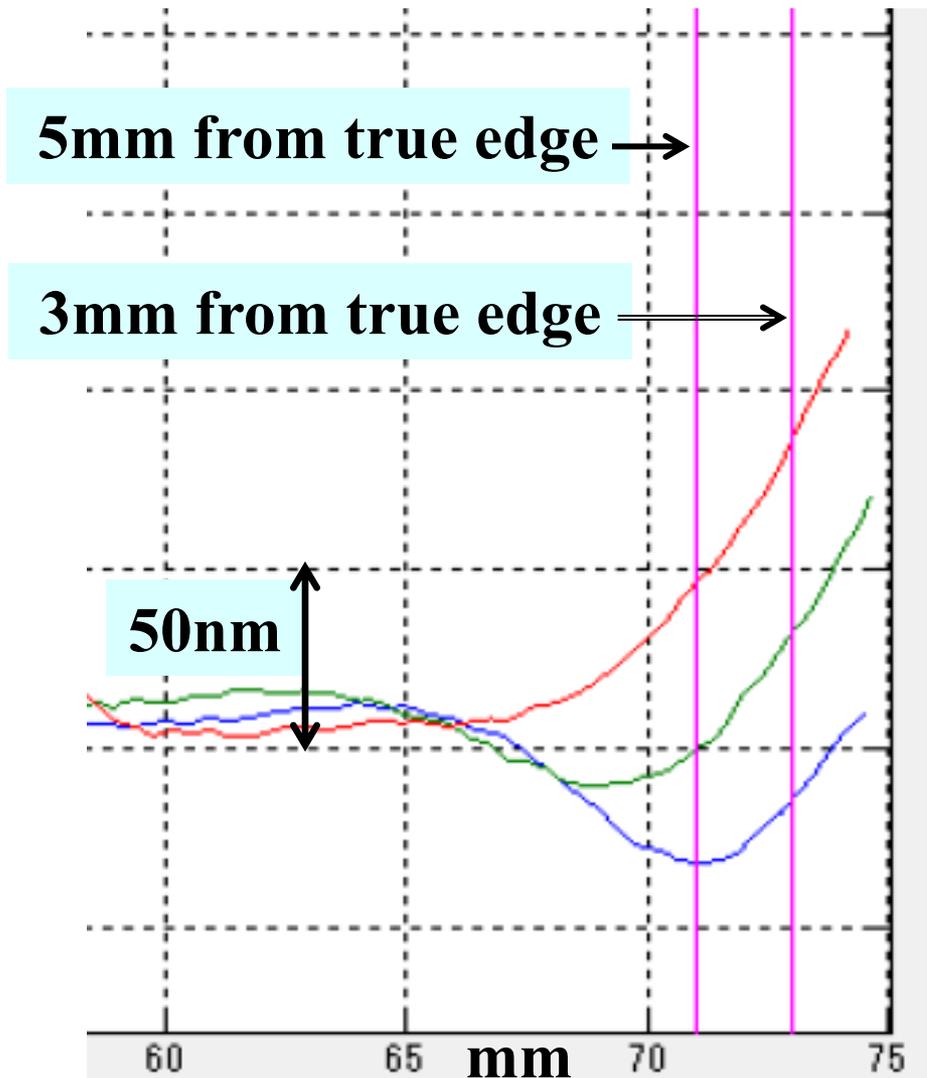
Photomask on Zeeko  
IRP200 machine



Corrective polishing  
within active area



# Results of three edge-lift regimes on a photomask



- Zeeko bonnet polishing alone exceeds edge-spec.
- Overall surface in active area:-
  - Input **611 nm PV**
  - Output **42nm PV**
  - Texture **< 0.5nm**

# Conclusions

- An end-to-end process chain
  - Part at final shape and size throughout
  - Well-suited to automated production-line
  - Edge control well understood
  - Applicable to various sectors ...from segmented telescopes to photomasks!
- Next – finish SPN01
- Then polish SPN03 (has been BoX-ground)

# Thank you!

## Acknowledgements

- NASA SBIR grant proposal No. S4.04-9574
- ESO: segment prototype contract
- Substantial financial support from:-
  - Glyndŵr University
  - UK-EPSC and STFC
  - Welsh Government:
- Zeeko Ltd: Build of IRP1600 machine and tech. support
- Cranfield University and Cranfield Precision Ltd: development of BoX grinder